PATENT APPLICATION 154

Group Art Unit: 2877

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Saburo KAMIYA

Application No.: 09/661,433 Examiner: S. Turner

Filed: September 13, 2000 Docket No.: 107312

For: EXPOSURE APPARATUS AND DEVICE PRODUCTION METHOD IN WHICH

POSITION OF REFERENCE PLATE PROVIDED ON SUBSTRATE STAGE IS

MEASURED (AS AMENDED)

INFORMATION DISCLOSURE STATEMENT

Director of the U.S. Patent and Trademark Office Washington, D.C. 20231

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the reference(s) listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

a. Attached is our check no. 134091 in the amount of \$180.00 in payment of the fee under 37 CFR \$1.17(p). Please credit or debit Deposit Account No. 15-0461 as needed to ensure consideration of the disclosed information. Two duplicate copies of this paper are attached.

Respectfully submitted

Mario A. Costantino Registration No. 33,565

MAC/ccs

Date: September 5, 2002

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